#### MILITARY SPECIFICATION

SEMICONDUCTOR DEVICE, TRANSISTOR, NPN, SILICON, HIGH-POWER TYPES 2N1722, TX2N1722, 2N1724, AND TX2N1724

This specification is mandatory for use by all Departments and Agencies of the Department of Defense.

#### 1. SCOPE

- 1.1 Scope. This specification covers the detail requirements for NPN, silicon, high-power transistors. The prefix "TX" is used on devices submitted to and passing the special process-conditioning, testing, and screening as specified in 4.5 through 4.5.9.1.
  - 1.2 Physical dimensions. Type 2N1722, see figure 1 (TO-53). Type 2N1724, see figure 2 (TO-61).

### \* 1.3 Maximum ratings.

$P_{T}^{1/}$ $T_{A} = 25^{\circ}C$	$P_{T}^{2/2}$ $T_{C} = 100^{\circ} C$	v <sub>CBO</sub>	v <sub>e BO</sub>	V <sub>CEO</sub>	$I_{\mathbf{C}}$	Top	T <sub>stg</sub>	Safe operating area (continuous DC)
w	w	<u>Vdc</u>	<u>Vdc</u>	<u>Vdc</u>	Adc	<u>°C</u>	°C	
3	50	175	10	80	5	+ 175	-65 to +200	(See figure 5)

1/ Derate linearly at 20 mW/°C for TA between +25°C and +175°C.  $\overline{2}/$  Derate linearly at 666 mW/°C for TC between +100°C and +175°C.

# \* 1.4 Primary electrical characteristics.

		VBE	V <sub>CE</sub> (sat)	C <sub>obo</sub>	${ t h_{FE}}$	h <sub>fe</sub>
Limit	θЈ-С	IC = 2 Adc I <sub>B</sub> = 200 mAdc	I <sub>C</sub> = 2 Adc I <sub>B</sub> = 200 mAdc	$V_{CB}$ = 15 Vdc $I_{E}$ = 0 100 kHz $\leq$ f $\leq$ 1 MHz	$V_{CE} = 15 \text{ Vdc}$ $I_{C} = 2 \text{ Adc}$	$V_{CE} = 15 \text{ Vdc}$ $I_{C} = 500 \text{ mAdc}$ $f = 10 \text{ MHz}$
	°C/W	Vdc	Vdc	<u>pf</u>		
Min Max	1.5	1.2	0.6	550	30 90	1 5

#### 2. APPLICABLE DOCUMENTS

2.1 The following documents, of the issue in effect on date of invitation for bids or request for proposal, form a part of the specification to the extent specified herein.

## SPECIFICATION

## MILITARY

MIL-S-19500 - Semiconductor Devices, General Specification for.

#### STANDARDS

#### MILITARY

 ${
m MIL\text{-}STD\text{-}202}$  - Test Methods for Electronic and Electrical Component Parts.  ${
m MIL\text{-}STD\text{-}750}$  - Test Methods for Semiconductor Devices.

(Copies of specifications, standards, drawings, and publications required by suppliers in connection with specific procurement functions should be obtained from the procuring activity or as directed by the contracting officer.)

\* 2.2 Other publications. The following documents form a part of this specification to the extent specified herein. Unless otherwise indicated, the issue in effect on date of invitation for bids or request for proposal shall apply.

#### NATIONAL BUREAU OF STANDARDS

Handbook H28 - Screw-Thread Standards for Federal Services.

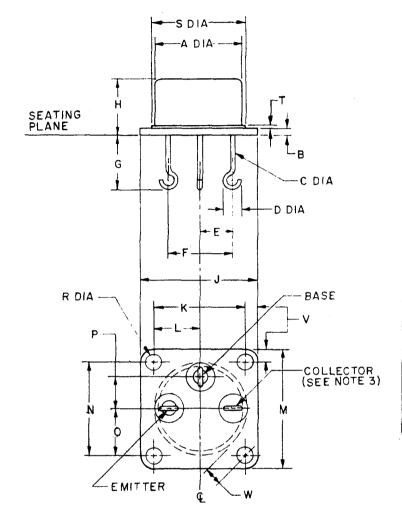
(Application for copies should be addressed to the Superintendent of Documents, Government Printing Office, Washington, D.C. 20402.)

## 3. REQUIREMENTS

- 3.1 General. Requirements shall be in accordance with MIL-S-19500, and as specified herein.
- 3.2 Abbreviations, symbols, and definitions. The abbreviations, symbols, and definitions used herein are defined in MIL-S-19500, and as follows:
  - IBC - - Forward-biased, base-collector current (dc), emitter open.
- 3.3 Design, construction, and physical dimensions. Transistors shall be of the design, construction, and physical dimensions shown on figures 1 and 2.
- 3.4 Performance characteristics. Performance characteristics shall be as specified in tables I, II, and  $\overline{\text{III}}$ , and as follows:
- 3.4.1 Process-conditioning, testing, and screening for "TX" type. Process-conditioning, testing, and screening for the "TX" types shall be as specified in 4.5.
- 3.5 Marking. The following marking specified in MIL-S-19500 may be omitted from the body of the transistor at the option of the manufacturer:
  - (a) Country of origin.
  - (b) Manufacturer's identification.
- 3.5.1 "TX" marking. Devices in accordance with the "TX" requirements shall include the marking "JANTX" preceding the type designation.

# 4. QUALITY ASSURANCE PROVISIONS

- 4.1 Sampling and inspection. Sampling and inspection shall be in accordance with MIL-S-19500, and as specified herein.
- 4.2 Qualification inspection. Qualification inspection shall consist of the examinations and tests specified in tables I, II, and III.



					T 5.
		DIMENSI	ONS		02
LTR	INC	HES	MILLIM	ETERS	OTES
	MIN	MAX	MIN	MAX	Š
A	.670	680	17.02	17.27	
В	.040	.055	1.02	1.40	
C	.035	.045	.89	1.14	4
D	.130	.150	3.30	3.81	4
Ε	.190	.210	4.83	5.33	
F	.385	.415	9.78	10.54	
G	.370	.420	9.40	10.67	4
Н	.305	.355	7.75	9.02	
J	.850	.870	21.59	22.10	
K	.670	.690	17.02	17.53	
L	.330	.350	8.38	8.89	
М	.850	.870	21.59	22.10	
N	.670	.690	17.02	17.53	
0	.330	.350	8.38	8.89	
Р	.190	.210	4.83	5.33	
R	.096	.106	2.44	2.69	7
S	.765	.785	19.43	19.94	
T	.030	.065	.76	1.65	
V	.075	.105	1.91	2.67	6
, W	.075		1.91		5

- NOTES:

  1. Metric equivalents (to the nearest .01 mm) are given for general information only and are based upon 1 inch = 25.4 mm.

  2. Lead spacing measured at seating plane.

  3. The collector shall be electrically connected to the case.

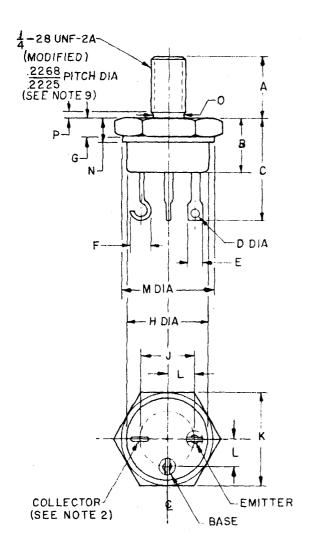
  4. All three leads.

  5. All four locations.

  6. All eight locations.

  7. All four holes.

FIGURE 1. Physical dimensions of transistor types 2N1722 and TX2N1722 (TO-53).



		DIMENSI	ONS		201-00
LTR	INC	HES	Ť		
LIX	MIN	MAX	MIN	MAX	ริ
Α	.422	.455	10.72	11.56	
В	.325	.460	8.26	11.68	
С	.640	.875	16.26	22.23	6
D	.047	.072	1.19	1.83	7
E	.095	.115	2.41	2.92	7
F		.150		3.81	
G	.090	.150	2.29	3.81	
Н	.570	.610	14.48	15.49	
J	.340	.415	8.64	10.54	
K	.667	.687	16.94	17.45	8
L	.170	.213	4.32	5.41	
M	.610	.687	15.49	17.45	
N		.270		6.86	
0	.220 .249 5.59 6		6.32		
Р		.090		2.29	

# NOTES:

- 1. Metric equivalents (to the nearest .01 mm) are given for general information only and are based upon 1 inch = 25.4 mm.
- The collector shall be electrically connected to the case.
   Lead spacing measured at seat only.
- 4. Position of leads in relation to hex is not controlled.
- 5. Maximum recommended mounting torque: 20 in-lb.
- 6. All three leads.
- 7. Two leads.
- 8. All three locations.9. Threads in accordance with Handbook H28.

FIGURE 2. Physical dimensions of transistor types 2N1724 and TX2N1724 (TO-61).

- 4.2.1 Qualification testing. The non-TX types shall be used for qualification testing. (Upon request to the qualifying activity, qualification will be extended to include the "TX" type of the device.)
- 4.3 Quality conformance inspection. Quality conformance inspection shall consist of group A, B, and C inspections. When specified in the contract or order, one copy of the quality conformance inspection data, pertinent to the device inspection lot, shall be supplied with each shipment by the device manufacturer (see 6.2).
- 4.3.1 Group A inspection. Group A inspection shall consist of the examinations and tests specified in table I.
- 4.3.2 Group B inspection. Group B inspection shall consist of the examinations and tests specified in table II.
- 4.3.3 Group C inspection. Group C inspection shall consist of the examinations and tests specified in table III. This inspection shall be conducted on the initial lot and thereafter every 6 months during production.
- 4.4 Methods of examination and test. Methods of examination and test shall be as specified in tables I, II, and III, and as follows:
- 4.4.1 Case-temperature control for  $|^h$ fe test. To maintain the case temperature at less than  $+40^{\circ}$ C for this test, the specified DC collector current should be applied for not longer than 10 seconds without employing a heat sink.
- 4.4.2 <u>Pulse measurements.</u> Conditions for pulse measurement shall be as specified in section 4 of MIL-STD-750.
- \* 4.4.3 <u>Solderability test.</u> The following particular procedural requirements shall apply for this test:
  - (a) Immersion depth for both transistors, shall be 0.200  $\pm\,0.025$  inches.
  - (b) Dwell time (immersion in the solder bath) shall be  $7 \pm 0.5$  seconds.

TABLE I. Group A inspection

There we have been some to set		MIL-STD-750	LTPD			Lir	nits	
Examination or test	Method	thod Details		тх	Symbol	Min	Max	Unit
Subgroup 1			10	10				
Visual and mechanical examination	2071							
Subgroup 2			5	3	:		:	
Breakdown voltage, collector to emitter	3011	Bias cond. D;I <sub>C</sub> = 200 mAdc pulsed (see 4.4.2)			BV <sub>CEO</sub>	80		Vdc
Breakdown voltage, emitter to base	3026	Bias cond. D; I <sub>E</sub> = 10 mAdc			BV <sub>EBO</sub>	10		Vdc
Collector to emitter cutoff current	3041	Bias cond. C; V <sub>CE</sub> = 60 Vdc			I <sub>CES</sub>		300	μAdo

TABLE I. Group A inspection - Continued

			MIL-STD-750	LT:	PD		Lin	nits	
	Examination or test	Method	Details	Non TX		Symbol	Min	Max	Unit
	Subgroup 2 - Continued								
	Collector to base cutoff current	3036	Bias cond. D; V <sub>CB</sub> = 175 Vdc		[	I <sub>CBO</sub>		5	m <b>A</b> dc
	Emitter to base cutoff current	3061	Bias cond. D; V <sub>EB</sub> = 7 Vdc			IEBO		400	μAdc
*	Subgroup 3			5	2				ļ
	Forward-current transfer ratio	3076	V <sub>CE</sub> = 15 Vdc; I <sub>C</sub> = 2 Adc; pulsed (see 4.4.2)			$^{ m h_{FE}}$	30	90	
	Forward-current transfer ratio	3076	V <sub>CE</sub> = 15 Vdc; I <sub>C</sub> = 5 Adc; pulsed (see 4.4.2)			h <sub>FE</sub>	15		
	Forward-current transfer ratio	3076	$V_{CE}$ = 15 Vdc; $I_{C}$ = 100 mAdc; pulsed (see 4.4.2)		:	h <sub>FE</sub>	30		
	Collector to emitter voltage (saturated)	3071	I <sub>C</sub> = 2 Adc; I <sub>B</sub> = 200 mAdc; pulsed (see 4.4.2)			V <sub>CE</sub> (sat)		0.6	<b>V</b> dc
	Base emitter voltage (saturated)	3066	Test cond. A; $I_C = 2$ Adc; $I_B = 200$ mAdc; pulsed (see 4.4.2)		 	V <sub>BE</sub> (sat)		1.2	Vdc
*	Subgroup 4			5	5				
	Magnitude of common emitter small-signal short-circuit forward-current transfer ratio	3306	V <sub>CE</sub> = 15 Vdc; I <sub>C</sub> = 500 mAdc; f = 10 MHz; (see 4.4.1)			h <sub>fe</sub>	1.0	5	
	Open-circuit output capacitance	3236	$V_{CB}$ = 15 Vdc; $I_E$ = 0; $100 \text{ kHz} \le f \le 1 \text{ MHz}$			C <sub>obo</sub>		550	pf
	Subgroup 5			10	10				
	High-temperature operation:		$T_A = 150^{\circ} C$						
	Collector to emitter cutoff current	3041	Bias cond. C; VCE = 60 Vdc			ICES		1.5	mAdc
	Collector to emitter cutoff current	3041	Bias cond. C; V <sub>CE</sub> = 120 Vdc			ICES		10	mAdc
	Low-temperature operation:		$T_A = -55^{\circ}C$						
	Forward-current transfer ratio	3076	V <sub>CE</sub> = 15 Vdc; I <sub>C</sub> = 2 Adc; pulsed (see 4.4.2)	j   		hFE	18		
				<u> </u>	<u> </u>			<u></u>	

TABLE II. Group B inspection

Examination or test		MIL-STD-750	LT	PD		Lin	nits	
	Method	Details	Non TX	тх	Symbol	Min	Max	Unit
Subgroup 1			20	20				
Physical dimensions	2066	(See figures 1 and 2.)						
Subgroup 2			10	10				
Solderability	2026	(See 4.4.3)						
Thermal shock (temperature cycling)	1051	Test cond. C						
Thermal shock (glass strain)	1056	Test cond. B						
Terminal strength (tension)	2036	Test cond. A; weight = 10 lbs ± 10 oz; time = 15 sec						
Terminal strength (stud torque) (for 2N1724 only)	2036	Test cond. D <sub>2</sub> ; torque = 20 in-lb; time = 15 sec						
Terminal strength (lead torque)	2036	Test cond. D1; torque = 6 in-oz; time = 15 sec						
Seal (leak-rate)		Method 112 of MIL-STD-202, test cond. C, procedure III; test cond. Afor gross leaks					5x10-7	atm cc/sec
Moisture resistance	1021	Omit initial conditioning						
End points:								
Breakdown voltage collector to emitter	3011	Bias cond. D; I <sub>C</sub> = 200 mAdc; pulsed (see 4.4.2)			BVCEO	80		Vdc
Collector to emitter cutoff current	3041	Bias cond. C; V <sub>CE</sub> = 60 Vdc			ICES		300	μ <b>Adc</b>
Forward-current transfer ratio	3076	$V_{CE}$ = 15 Vdc; $I_{C}$ = 2 Adc; pulsed (see 4.4.2)			h <sub>FE</sub>	30	90	
Subgroup 3			10	10				
Shock	2016	Nonoperating; 1500 G, 0.5 msec, 5 blows in each orientation: $X_1$ , $Y_1$ , $Y_2$ , and $Z_1$						
Vibration, variable frequency	2056							
Constant acceleration	2006	5000 G; in each orientation: $X_1$ , $Y_1$ , $Y_2$ , and $Z_1$						
End points: (Same as subgroup 2)						į		

TABLE II. Group B inspection - Continued

		MIL-STD-750	LTF	מי		Lin	nits	
Examination or test	Method	Details	Non TX	тх	Symbol	Min	Max	Unit
Subgroup 4			20	20				
Salt atmosphere (corrosion)	1041							
End points: (Same as subgroup 2)								
Subgroup 5			10	10				
Safe operating area (continuous DC)	See figures 4 and 5	$ \begin{vmatrix} T_C = +100^{\circ}C; \text{ time } = 60 \text{ sec}; \\ t_r \leq 6 \text{ sec}; \\ t_f \leq 6 \text{ sec}; 1 \text{ cycle} $						
Test 1		$V_{CE} = 10 \text{ Vdc}; I_{C} = 5 \text{ Adc}$						
Test 2		$V_{CE} = 80 \text{ Vdc};$ $I_{C} = 250 \text{ mAdc}; T_{C} = +145 ^{\circ}\text{C}$						
End points: (Same as subgroup 2)								
Subgroup 6			10	10				
Unclamped inductive sweep	See figures 6 and 7							
Test 1		$T_A = 25$ °C; $I_C = 5 \text{ Adc}; L = 2 \text{ mH}$						
Test 2		T <sub>A</sub> = 25°C; I <sub>C</sub> = 1 Adc; L = 20 mH						
End points: (Same as subgroup 2)								
Subgroup 7			10	10				
Clamped inductive sweep	See figures 8 and 9	T <sub>A</sub> = 25°C; I <sub>C</sub> = 5 Adc; L = 20 mH						
End points: (Same as subgroup 2)								
Subgroup 8			λ=1	.0 λ=	:5			
High-temperature life (nonoperating)	1031	$T_{\text{stg}} = +200^{\circ} \text{C}$						

		MIL-STD-750	LT	PD		Lin	nits	
Examination or test	Method	Method Details		ТX	Symbol	Min	Max	Unit
Subgroup 8 - Continued								
End points: 1/								ļ <b> </b>
Breakdown voltage collector to emitter	3011	Bias cond. D; I <sub>C</sub> = 200 mAdc; pulsed (see 4.4.2)			BV <sub>CEO</sub>	80		Vdc
Change in collector to emitter cutoff current	3041	Bias cond. C; VCE = 60 Vdc			ΔI <sub>CES</sub>	 	2/	
Change in forward-current transfer ratio	3076	V <sub>CE</sub> = 15 Vdc; I <sub>C</sub> = 2 Adc pulsed (see 4.4.2)			Δh <sub>FE</sub>		+20 -10	% chang from initial group A reading
Emitter to base cutoff current	3061	Bias cond. D; V <sub>E B</sub> = 5 Vdc			I <sub>EBO</sub>		500	μ <b>Ad</b> c
Subgroup 9			λ=10	λ=5			1	
Steady-state operation life	1026	$T_C = +100^{\circ}C;$ $P_C = 50 \text{ W}; V_{CE} = 40 \text{ Vdc}$						
End points: (Same as subgroup 8)								

<sup>1/</sup>The Δ limits for the I<sub>CES</sub> and h<sub>FE</sub> tests apply to the change from original value measured for the sample units during group A inspection. 2/ (See footnote 1/above.) Where original group A value is less than 50  $\mu$ Adc, a Δ of 50  $\mu$ Adc maximum

TABLE III. Group C inspection

		MIL-STD-750	LT	PD		Limits		
Examination or test	Method	Details	Non TX	тх	Symbol	Min	Max	Unit
Subgroup 1			15	15				
Barometric pressure, reduced (altitude operation)	1001	Pressure = 8 mm Hg, normal mounting; time = 60 sec						
Measurement during test:								
Collector to base cutoff current	3036	Bias cond. D; V <sub>CB</sub> = 175 Vdc			I <sub>CBO</sub>		10	mAdc
Subgroup 2			15	15				
Thermal resistance	3136	$T_1 = T_C = 110 \pm 10^{\circ} \text{C};$ $T_2 = T_J = 165 + 10^{\circ} \text{C};$ $I_{BC}(\text{measurement}) = 50 \text{ mAc}$			θJ-C		1.5	°C/W

<sup>2/(</sup>See footnote 1/above.) Where original group A value is less than 50  $\mu$ Adc, a  $\Delta$  of 50  $\mu$ Adc maximum is applicable; for original group A values from 50  $\mu$ Adc to 300  $\mu$ Adc, a maximum  $\Delta$  of 100% of the original value is applicable.

- 4.5 Process-conditioning, testing, and screening for "TX" type. The procedure for process-conditioning, testing, and screening shall be in accordance with 4.5.1 through 4.5.9.1 and figure 3. Process-conditioning shall be conducted on 100 percent of the lot, prior to submission of the lot to the tests specified in tables I, II, and III. (At the option of the manufacturer, the non-TX type may be subjected to process-conditioning and testing.)
- \* 4.5.1 Quality assurance (lot verification). Quality assurance shall keep lot records for 3 years, minimum, monitor for compliance to the prescribed procedures, and observe that satisfactory manufacturing conditions and records on lots are maintained for these devices. The records shall be available for review by the customer at all times. The quality assurance monitoring shall include, but not be limited to: Process-conditioning, testing, and screening. (The conditioning and screening tests performed as standard-production tests need not be repeated when these are predesignated and acceptable to the Government as being equal to or more severe than specified herein and the relative process-conditioning sequence is maintained.)
- 4.5.2 <u>High-temperature storage.</u> All devices shall be stored for at least 24 hours at a minimum temperature  $(T_A)$  of 200° C.
- 4.5.3 Thermal shock (temperature cycling). All devices shall be subjected to thermal shock (temperature cycling) in accordance with MIL-STD-750, method 1051, test condition C, except that 10 cycles shall be continuously performed and the time at the temperature extremes shall be 15 minutes, minimum.
- \* 4.5.4 Reverse bias. All devices shall be subjected to a reverse bias,  $V_{CB}$  = 120 Vdc for 48 hours minimum at  $T_A$  = +150°C. The transistors shall be cooled to room ambient temperature (+25°C) before removal of the impressed voltage.
- \* 4.5.5 Acceleration. All devices shall be subjected to acceleration test in accordance with MIL-STD- $\overline{750}$ , method 2006, with the following exceptions: The test shall be performed one time in the Y<sub>1</sub> orientation only, at a peak level of 5,000 G minimum. The one minute hold-time requirement shall not apply.
- 4.5.6 Hermetic seal (fine-leak) test. All devices shall be fine-leak tested in accordance with MIL-STD-202, method 112, test condition C, procedure IIIa or IIIb (using the applicable conditions of 4.5.6.1 or 4.5.6.2), except that the gross-leak test shall be as specified in 4.5.6.3.
- \* 4.5.6.1 Conditions for procedure IIIa. The devices shall be placed in a sealed chamber and pressurized to 50 psig minimum with pure commercial grade helium gas for a minimum of 4 hours. The devices shall then be removed from the chamber and within 30 minutes be subjected to a helium leak detection test. Devices shall be rejected that exhibit a leak rate of 5x10-7 cubic centimeter (cc) of helium per second when measured at a differential pressure of one atmosphere. All devices exhibiting this leakage rate or greater shall be removed from the lot.
- \* 4.5.6.2 Conditions for procedure IIIb. The devices shall be placed in an activation tank, pressurized with Krypton 85 tracer gas in a nitrogen solution, for sufficient time to detect a leak rate of  $1\times10^{-8}$  atmospheric cubic centimeters per second (atm cc/sec). Within four hours after subjection to this pressurization, the leak rate of the devices shall be determined on an attribute basis using the general equation shown below. Any device exhibiting a leak rate equal to or greater than  $1\times10^{-8}$  atm cc/sec shall be removed from the lot. The general equation for use with radioactive gas leak test equipment is:

$$Q = \frac{R}{SKT(P_e^2 - P_i^2)}$$

where:

= leak rate in atm cc/sec.

= net counting rate of tested part above background in cts/min.

= specific activity of the test gas mixture in  $\mu$ Ci/atm cc.

= counting efficiency of the system for the given part in cts/min  $\mu$ Ci.

 $P_{e}$  = pressure of test gas in activation tank during pressurization in atm abs.

 $P_i$  = pressure inside part under test in atm abs.

= duration of pressurization in test gas mixture in seconds.

\* 4.5.6.3 Hermetic seal (gross-leak) test. All devices shall be tested for gross-leaks by immersing in a non-corrosive suitable liquid at approximately 100°C for a minimum of 15 seconds and observed for bubbles. All devices that bubble shall be removed from the lot.

4.5.7 Preburn-in tests. The parameters  $I_{CES}$ ,  $h_{FE}$ , and  $I_{EBO}$  of table IV shall be measured and the data recorded for all devices in the lot. All devices shall be handled or identified such that the delta end points can be determined after the burn-in test. All devices which fail to meet these requirements shall be removed from the lot and the quantity removed shall be noted on the lot history.

	MII	STD-750		Lim			
Test	Method	Details	Symbol	Min	Max	Unit	
Collector to emitter cutoff current	3041	Bias cond. C; V <sub>CE</sub> = 60 Vdc	I <sub>CES</sub>		300	μAdc	
Forward-current transfer ratio	3076	V <sub>CE</sub> = 15 Vdc; I <sub>C</sub> = 2 Adc; pulsed (see 4.4.2)	hFE	30	90		
Emitter to base cutoff current	3061	Bias cond. D; V <sub>EB</sub> = 5 Vdc	I <sub>E BO</sub>		400	μ <b>A</b> dc	

TABLE IV. Burn-in test measurements

\* 4.5.8 Burn-in test. All devices shall be operated for 168 hours minimum under the following conditions:

$$T_C = 100$$
°C  $V_{CB} = 40 \text{ Vdc}$   $P_T = 50 \text{ W}$ 

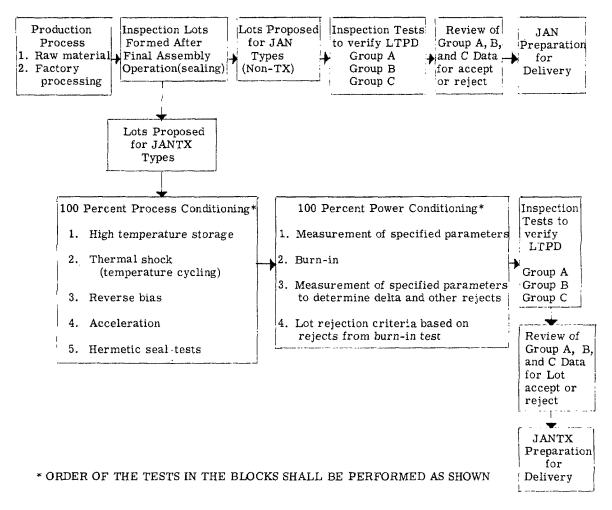
\* 4.5.9 Post burn-in tests. The parameters  $I_{CES}$ ,  $h_{FE}$  and  $I_{EBO}$  of table IV shall be retested after burn-in and the data recorded for all devices in the lot. The parameters measured shall not have changed during the burn-in test from the initial value by more than the specified amount as follows:

> $_{\Delta h_{ ext{FE}}}^{\Delta I_{ ext{CES}}}$ = 100 micro-amperes.

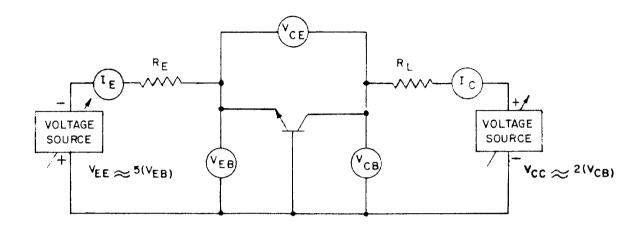
=  $\pm 15$  percent.

= 100 percent or 100 micro-amperes, whichever is greater.

4.5.9.1 Burn-in test failures (screening). All devices that exceed the delta ( $\Delta$ ) limits of 4.5.9 or the limits of table IV after burn-in, shall be removed from the inspection lot and the quantity removed shall be noted on the lot history. If the quantity removed after burn-in should exceed 10 percent of the number of devices subjected to the burn-in test, then the entire inspection lot shall be unacceptable for the "TX" type.



- \* FIGURE 3. Order of procedure diagram for JAN (Non-TX) and JANTX types.
  - 5. PREPARATION FOR DELIVERY
  - 5.1 See MIL-S-19500, section 5.
  - 6. NOTES
  - 6.1 Notes. The notes specified in MIL-S-19500 are applicable to this specification.
  - 6.2 Ordering data. Inspection data (see 4.3).



#### Procedure:

- a. Starting with  $V_{CC}$  and  $V_{EE}$  at a low value, increase  $V_{CC}$  to approximately obtain specified  $V_{CE}$ . Increase  $V_{CE}$  and subsequently adjust  $V_{EE}$  to obtain specified  $V_{CE}$  and  $V_{CE}$  ar
- b. Decrease  $V_{CC}$  to obtain  $V_{CE}$  near zero. Turn off  $V_{EE}$ . Turn off  $V_{CC}$ .
- c. The transistor shall be considered a failure if collector current (I\_C) varies  $\pm 10\%$  during operation, or exceeds the end points.

FIGURE 4. Safe operating area test circuit (continuous DC).

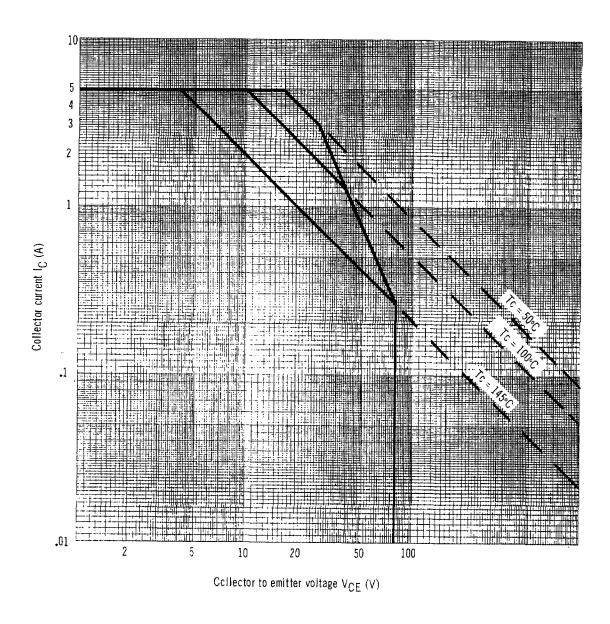
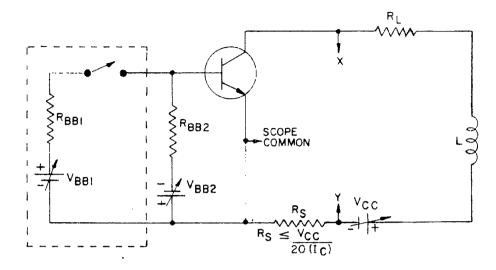


FIGURE 5. Maximum safe operating area graph - Continuous DC.



Test No. 1: TA = 25°C RBB1 = 5 ohms = 5 Adc V<sub>BB1</sub> = 15 Vdc R<sub>BB2</sub> = 10 ohms  $V_{BB2} = 5 \text{ Vdc}$  $R_S^{--}$  = .1 ohm 1% non-inductive

 $V_{CC} = 18 \text{ Vdc}$ 

= 1 mH, .56 ohm (Miller 7870. Two each are used

 $R_{\mathsf{L}}$ = 5 ohms in series, or equivalent).

Note: Duty cycle ≤10%.

Test No. 2: TA = 25°C I<sub>C</sub> = 1 Adc R BB1 = 5 ohms V BB1 = 8 Vdc RBB2 = 10 ohms

 $V_{BB2} = 5 \text{ Vdc}$   $R_S = .1 \text{ ohm } 1\% \text{ non-inductive}$ 

 $V_{CC} = 13.5 \text{ Vdc}$ 

= 20 mH, .22 ohm (Stancer C-2688, 10 mH, .11 ohm. Two = 5 ohms each are used in series, or equivalent).

Note: Duty cycle ≤ 10%

Procedure: Starting at a low value, adjust VBB2 and VCC to the specified levels. With the duty cycle and repetition rate preset to specified conditions, increase VBB1 voltage to achieve the specified IC; and the output wave form (IC vs  $V_{CE}$ ) shall be observed on the scope.

When the transistor is turned off (switched), the observed trace shall be a smooth curve between saturation and cut-off. Any oscillations or inconsistencies on the trace shall be cause for rejection.

FIGURE 6. Unclamped inductive sweep test circuit.

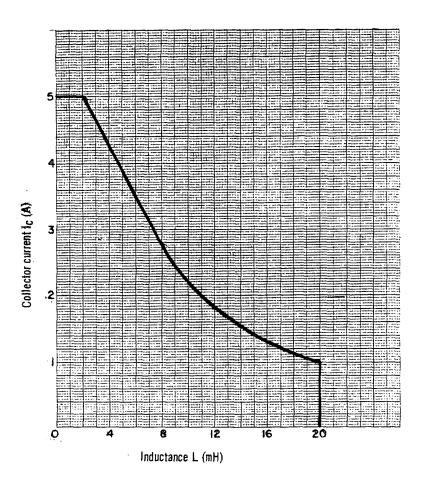
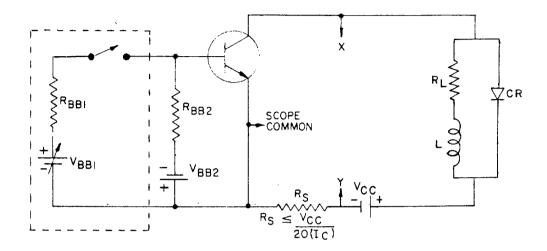


FIGURE 7. Safe operating area for switching between saturation and cutoff - unclamped inductive load.



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\begin{array}{lll} T_A &= 25 ^{\circ} C \\ I_C &= 5 \text{ Adc} \\ RBB1 &= 5 \text{ ohms} \\ VBB1 &= 15 \text{ Vdc} \\ RBB2 &= 10 \text{ ohms} \\ VBB2 &= 5 \text{ Vdc} \\ R_S &= .1 \text{ ohm, } 1 \% \text{ non-inductive} \\ R_L &= 35 \text{ ohms} \\ C_R &= 1 \text{N}1204 \\ L &= 20 \text{ mH, .22 ohm (Stancor C-2688, } 10 \text{ mH, .} 11 \text{ ohm, two} \\ VCC &= 175 ^{+}_{-5} \text{ Vdc} & \text{ each are used in series, or equivalent).} \end{array}
```

MCTE: Clamp voltage, all types =  $175_{-5}^{+0}$  Vic.

Procedure: Starting at a low value, adjust  $V_{BB2}$  and  $V_{BB1}$  to the specified levels. With a 10% duty cycle and 5 ms pulse width preset, increase  $V_{CC}$  voltage to achieve the specified  $I_C$ ; and the output waveform ( $I_C$  vs  $V_{CE}$ ) shall be observed on the scope.

When the transistor is turned off (switched), the observed trace shall be a smooth curve between saturation and cut-off. Any oscillations or inconsistencies on the trace shall be cause for rejection.

FIGURE 8. Clamped inductive sweep test circuit.

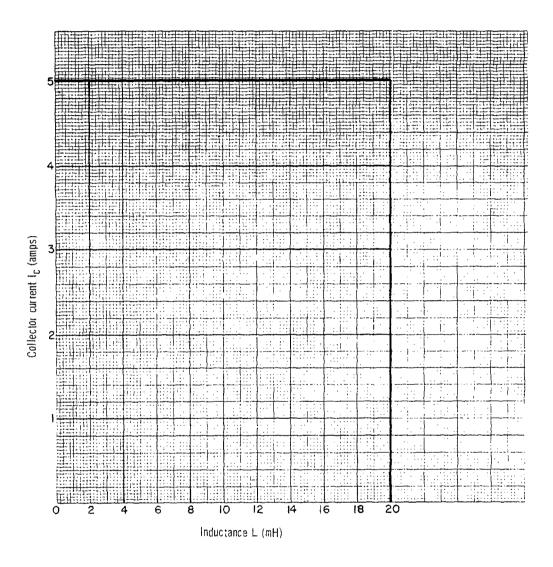


FIGURE 9. Safe operating area for switching between saturation and cutoff - clamped inductive load.

6.3 Changes from previous issue. The margins of this specification are marked with an asterisk to indicate where changes (additions, modifications, corrections, deletions) from the previous issue were made. This was done as a convenience only and the Government assumes no liability whatsoever for any inaccuracies in these notations. Bidders and contractors are cautioned to evaluate the requirements of this document based on the entire content irrespective of the marginal notations and relationship to the last previous issue.

Custodians:

Army - EL Navy - EC

Air Force - 11

Review activities:

Army - EL, MU, MI Navy - EC, SH

Air Force - 11, 17, 85

DSA - ES

User activities:

Army - EL, SM Navy - CG, MC, OS, AS

Air Force - 19

Preparing activity: Army - EL

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